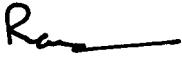


INFORMATION DISCLOSURE STATEMENT BY APPLICANT		Attorney Docket Number	6333-67325
		Application Number	Not yet assigned
		Filing Date	Herewith
		First Named Inventor	Dickey
		Art Unit	Not yet assigned
		Examiner Name	Not yet assigned
U.S. PATENT DOCUMENTS			
Examiner's Initials*	Cite No. (optional)	Number	Date
✓		4,058,430	11/15/77
		4,389,973	6/28/83
		5,091,320	2/25/92
		5,257,132	10/26/93
		5,321,713	6/14/94
		5,438,952	8/8/95
		5,458,084	10/17/95
		5,677,594	10/14/97
		5,711,811	1/27/98
		5,712,528	1/27/98
		5,785,756	7/28/98
		5,804,919	9/8/98
		5,872,655	2/16/99
✓		6,449,403	9/10/02

EXAMINER SIGNATURE: 	DATE CONSIDERED: 5-25-07
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT		Attorney Docket Number	6333-67325
		Application Number	Not yet assigned
		Filing Date	Herewith
		First Named Inventor	Dickey
		Art Unit	Not yet assigned
		Examiner Name	Not yet assigned
FOREIGN PATENT DOCUMENTS			
Examiner's Initials*	Cite No. (optional)	Number	Date
		JP59045408	3/14/84
		JP6196809	7/15/94
		JP62002213	1/8/87
Examiner's Initials*	Cite No. (optional)	OTHER DOCUMENTS	
		T. Suntola, "Cost-effective Processing By Atomic Layer Epitaxy," <u>Thin Solid Films</u> , 225:96-98 (1993).	
		T. Suntola, "Atomic Layer Epitaxy," <u>Thin Solid Films</u> , 216:84-89 (1992).	

NOT PROVIDED BY APPLICANT

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT <small>JAN 26 2004</small> <small>RECEIVED PATENT & TRADEMARK OFFICE JAN 26 2004</small>		Attorney Docket Number	6333-67325
		Application Number	10/713,362
		Filing Date	November 14, 2003
		First Named Inventor	Dickey et al.
		Art Unit	
		Examiner Name	

U.S. PATENT DOCUMENTS

Examiner's Initials*	Cite No. (optional)	Number	Date	Name
✓		4,915,476	4-10-90	Hall et al
		5,102,694	4-7-92	Taylor et al.
		5,164,040	11-17-92	Eres et al.
		5,458,084	10-17-95	Thorne et al.
		5,472,505	12-5-95	Lee et al
		5,724,144	3-3-98	Muller et al.
✓		5,916,365	6-29-99	Sherman

FOREIGN PATENT PUBLICATION

Examiner's Initials*	Cite No. (optional)	Number	Date	Country
✓		0 416 251 A2	3-13-91	European
✓		61018124	1-27-86	Japanese Abstract

Examiner's Initials*	Cite No. (optional)	OTHER DOCUMENTS
✓		Kukli et al., "Real-Time Monitoring in Atomic Layer Deposition of TiO ₂ from TiLi ₄ and H ₂ O—H ₂ O ₂ " Langmuir 2000, 16: 8122-8128
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✓		Aarik et al., "Anomalous effect of temperature on atomic layer deposition of titanium dioxide", Journal of Crystal Growth 220 (2000) 531-537

EXAMINER SIGNATURE: <i>Ran</i>	DATE CONSIDERED: <i>S-25-07</i>
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